

06/15/01  
U.S. PTO  
06/15/01

Docket No. AM 1562D1

JC978 U.S. PTO  
06/09/882141  
06/15/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Divisional Application of  
JOAN WANG

Parent Serial No.: 08/867,229

Parent Filed: June 2, 1997

For: METHOD OF ETCHING HIGH ASPECT  
RATIO OPENINGS IN SILICON

PETITION UNDER 37 CFR 1.84(b)(1)

To: Assistant Commissioner for Patents  
Washington, DC 20231

Sir:

Applicants petition that the Assistant Commissioner accept  
THREE sheets of photomicrographs bearing Figures 3, 4, 5, 6, 7  
and 8 thereon. Three copies of each sheet are attached.

Please charge the Petition fee of \$130.00 to Deposit Account  
13-4542. A duplicate of this Petition is attached.

Respectfully submitted,

JOAN WANG

By



Birgit E. Morris

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Please continue to send all correspondence to

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I hereby certify that this correspondence is  
being deposited with the United States Postal  
Service as first class mail in an envelope  
addressed to The Assistant Commissioner for  
Patents, Washington, DC 20231, on

June 15, 2001  
Date of Deposit

William E. Morris  
Name of person making deposit

Signature